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APPLICANT Garo J. Derderian

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U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
TZ	AA	2002/0064915A1	05/2002	Kitamura			
TZ	AB	2001/0023110A1	09/2001	Fukuzumi et al			
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AM							
	AN							
	AO							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

TZ	AP		A.W. Ott, et al., "Atomic layer controlled deposition of Al ₂ O ₃ films using binary reaction sequence chemistry" Applied Surface Science (107) 1996, pps. 128-136.
	AQ		
	AR		

EXAMINER

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DATE CONSIDERED

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